

ABSTRACT OF THE DISCLOSURE

An interferometric measuring device for measuring the shape of a surface of an object having a radiation source which emits a short-coherent radiation, a beam splitter for forming an object beam which is directed via an object light path to the object, and a reference beam which is directed via a reference light path to a reflective reference plane, and having an image converter which picks up the radiation reflected back by the surface and the reference plane and brought to interference, and sends it to an analyzing device for determining a measuring result pertaining to the surface, the optical length of the object light path being changed relative to the optical length of the reference light path for analyzing the interference peak.